

CreaTec Beam Flux Monitor is used for the precise measurement of the beam equivalent pressure (BEP) in MBE systems. A Bayard-Alpert type flux gauge on a movable positioning system allows the measurement in sample position. High precision electronics guarantee a stable detection of the investigated molecular beam intensity. A computer system for control is optional. Filaments can be easily exchanged.

TYPE	BAF
MEASUREMENT SYSTEM	Bayard-Alpert ion gauge
LINEAR STROKE	150 - 600 mm <small>manually operated</small>
BAKE-OUT TEMPERATURE	250 °C
CONTROLLER TYPE	1-channel UHV-gauge controller
CONTROLLER RANGE	1×10^{-1} - 1×10^{-12} mbar
CONTROLLER INTERFACE	RS232 RS485
FLANGE SIZE	DN 40 CF 63 <small>or as specified</small>
MAX. OUTER DIAMETER	34mm 50 mm <small>or as specified</small>
HOME	as specified
FILAMENT	dual filament Yttrium coated Iridium <small>others on request</small>

Options

- Integrated shutter
- Quartz crystal monitor instead of Bayard-Alpert Ionisation Gauge
- Valve with by-pass
- Motorized version
- Filament replacement kit
- cVac software control

